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**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**  
(Use as many sheets as necessary)

**Complete if Known**

Application No.:	10/549,865
Filing Date:	July 28, 2006
First Named Inventor:	Victor Higgs
Art Unit:	2886
Examiner Name:	Isiaka O. Akanbi

Sheet 1 of 5 Attorney Docket No.: NAN65 US (8037)

**U.S. PATENT DOCUMENTS**

Examiner Initials*	Cite No.	Document Number	Publication Date	Name of Patentee or Application of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear (if known)
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**NON PATENT LITERATURE DOCUMENTS**

Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
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